



Gm 2876
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PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:
KEVIN R. LENSING

Serial No.: 09/897,205

Filed: July 2, 2001

For: METHOD OF USING SCATTEROMETRY
MEASUREMENTS TO CONTROL
PHOTORESIST ETCH PROCESS

Examiner: Kumiko C. Koyama

Group Art Unit: 2876

Att'y Docket: 2000.071900/TT4369

TECHNOLOGY CENTER 2800

APR 30 2003

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RESPONSE TO OFFICE ACTION DATED MARCH 24, 2003

Assistant Commissioner for Patents
Washington, D.C. 20231

Sir:

CERTIFICATE OF MAILING 37 C.F.R. 1.8	
I hereby certify that this correspondence is being deposited with the U.S. Postal Service with sufficient postage as First Class Mail in an envelope addressed to: Assistant Commissioner for Patents, Washington, D.C. 20231, on the date below:	
April 22, 2003 Date	 Signature

This paper is submitted in response to the Office Action dated March 24, 2003, for which the three-month date for response is June 24, 2003.

No fees are believed to be due in connection with the present paper. However, if any fees are due, the Assistant Commissioner is authorized to deduct such fees required under 37 C.F.R. §§ 1.16 to 1.21 from the Advanced Micro Devices, Inc. Deposit Account No. 01-0365/TT4369. In the event the monies in that account are insufficient, the Assistant Commissioner is authorized to withdraw funds from Williams, Morgan & Amerson, P.C. Deposit Account No. 50-0786/2000.071900.

Reconsideration of the application in view of the following remarks is respectfully requested.